

METHOD FOR MANUFACTURING AND CONTROLLING  
STRUCTURES AND PATTERNS OF SOLUBLE AND COLLOIDAL  
SUBSTANCES BY PRINTING ON THE MICROMETER AND  
NANOMETER SCALE AND WITH REDUCTION OF THE  
5 DIMENSIONS OF THE STAMP'S FEATURES

ABSTRACT OF THE DISCLOSURE

10 A printing process for obtaining patterns of nanometer and  
micrometer dimensions on a substrate, comprising i) the application of a  
solution or suspension of an imprinting material to the substrate, ii) the  
positioning, without applying pressure, of a stamp provided with relief  
patterns at a distance of 0 nm to 500  $\mu\text{m}$  from the substrate, and iii) the  
15 evaporation of the solution or suspension.

(Figure 1)